

CLAIM AMENDMENTS

Please amend Claims 25 and 29 as set forth below.

1-18. (Cancelled)

C' 19. (Previously Presented) A liquid discharge head, comprising:
a plurality of discharge ports for discharging liquid;
a plurality of liquid flow paths communicated with each of said
discharge ports to supply liquid to each of said discharge ports;
a substrate provided with heat generating members for creating a
bubble in the liquid;
a movable member arranged in each of said plural liquid flow paths,
the movable member having a free end on said discharge port side to face said heat
generating member; and
a pedestal portion formed on said substrate for supporting said
movable member,
said movable member having a property of being curved by heat,
and a portion corresponding to a movable range being separated by heating from said
substrate.

20. (Previously Presented) A liquid discharge head, comprising:
a plurality of discharge ports for discharging liquid;
a plurality of liquid flow paths communicated with each of said
discharge ports to supply liquid to each of said discharge ports;

a substrate provided with heat generating members for creating a bubble in the liquid;

a movable member arranged in each of said plural liquid flow paths and having a free end on said discharge port side to face said heat generating member; and

a pedestal portion formed on said substrate for supporting said movable member,

a portion of said movable member corresponding to a movable range being separated from said substrate by means of an inner stress and a function of a releasable layer formed on said substrate.

21. (Previously Presented) A liquid discharge head, comprising:

a plurality of discharge ports for discharging liquid;

a plurality of liquid flow paths communicated with each of said discharge ports to supply liquid to each of said discharge ports;

a substrate provided with a heat generating member for creating a bubble in the liquid;

a movable member arranged in said plural liquid flow paths, the movable member having a free end on said discharge port side to face said heat generating member; and

a pedestal portion formed on said substrate for supporting said movable member,

a portion of said movable member corresponding to a movable range being provided with a recessed part on the portion adjacent to said pedestal portion.

22. (Previously Presented) A liquid discharge head having a substrate according to Claim 25, comprising:

a discharge port for discharging liquid; and

a liquid flow path communicated with said discharge port to supply liquid to said discharge port;

wherein said movable member is arranged in said liquid flow path, the movable member having a free end on said discharge port side to face said heat generating member, and said free end being positioned downstream of the area center of said heat generating member.

23. (Original) A liquid discharge head according to Claim 22, wherein said movable member is formed by silicon nitride with impurities being added thereto.

24. (Previously Presented) A liquid discharge head, comprising:

a discharge port for discharging liquid;

a liquid flow path communicated with said discharge port to supply liquid to said discharge port;

a substrate provided with a heat generating member for creating a bubble in the liquid; and

a movable member arranged on said substrate in said liquid flow path, the movable member having a free end on said discharge port side to face said heat generating member, and said free end being positioned downstream of the area center of said heat generating member,

wherein said movable member is formed by a silicon nitride multi-layered film with the compositions being changed or impurities being added thereto.

25. (Currently Amended) A substrate for use in a liquid discharge head, said substrate being provided with a heat generating member for creating a bubble in the liquid, and a cantilever type movable member arranged to face said heat generating member with a specific gap therebetween,

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said movable member being formed from either one of silicon nitride, diamond, amorphous carbon hydride, silicon carbide, and silicon oxide, and being fixed to said substrate.

26. (Previously Presented) A substrate for use in a liquid discharge head according to Claim 25, wherein said movable member is formed by silicon nitride having impurities being added thereto.

27. (Previously Presented) A substrate for use in a liquid discharge head, said substrate being provided with a heat generating member for creating a bubble in the liquid, and a cantilever type movable member arranged to face said heat generating member with a specific gap therebetween, said movable member being fixed to said substrate and being formed by a silicon nitride multi-layered film with the compositions being changed or impurities being added thereto.

28. (Previously Presented) A method for manufacturing a substrate for use in a liquid discharge head, comprising the steps of providing the substrate with a heat

generating member for generating a bubble in the liquid, and with a cantilever type movable member arranged to face said heat generating member with a predetermined gap therebetween, wherein said movable member is provided on said substrate by a photolithographic method.

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29. (Currently Amended) A method for manufacturing a substrate for use in a liquid discharge head according to Claim 28, wherein the movable member is formed by any one of silicon nitride, diamond, amorphous carbon hydride, silicon carbide, or silicon oxide.
